

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Tatsutoshi SUZUKI

Serial No.: NEW APPLICATION

Divisional of : 10/026,504

Filed: April 21, 2004

For: TURNING TOOL FOR GROOVING POLISHING PAD, APPARATUS AND METHOD
OF PRODUCING POLISHING PAD USING THE TOOL, AND POLISHING PAD
PRODUCED BY USING THE TOOL

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

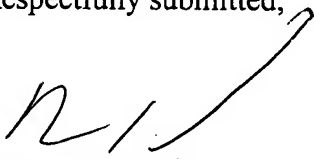
Sir:

Pursuant to 37 C.F.R. §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached Form PTO-1449. Copies of the references listed on Form PTO-1449 are attached.

It is respectfully requested that the information be expressly considered during the prosecution of this application, that these references be made of record therein and appear among the "References Cited" on any patent to issue therefrom, and that an initialed copy of the PTO-1449 be returned to the undersigned.

Respectfully submitted,

Date: 04/21/04



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INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional) KASA:019A

SERIAL NO.: NEW APPLICATION

APPLICANT(s) Tatsutoshi SUZUKI

FILING DATE: April 21, 2004

Group Art Unit

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	US	5,921,855	7/99	Osterheld et al.	451	527	
	US	5,984,769	11/99	Bennett et al.	451	527	
	US	6,241,585	6/01	White	451	41	
	US	6,572,445	6/03	Laursen	451	10	
	US	6,561,891	5/03	Eppert, Jr. et al.	451	530	
	US	6,238,271	5/01	Cesna	451	41	
	US	5,398,458	3/95	Henriksen et al.	125	13.01	
	US	6,641,471	11/03	Pinheiro et al.	451	526	
	US	6,602,436	8/03	Mandigo et al.	216	88	

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	JP	11-70463	3/99	JAPAN (English Abst.)			X	
	JP	47-16044	6/72	JAPAN (Concise Explanation)			X	
	JP	63-22002	6/88	JAPAN (Concise Explanation)			X	
	JP	2000-94303	4/00	JAPAN (English Abst.)			X	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

			The Science of CMP; August 20, 1997; pages 113-119; Chapter 4, Part III "Structure and Feature of the polishing pad".
EXAMINER			DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.